## Electrodeposited ruthenium oxide (RuO<sub>2</sub>) films for electrochemical supercapacitors

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Ruthenium oxide (RuO<sub>2</sub>) has been widely used because of its good catalytic properties in electrochemicals (e.g., chlorine and oxygen evolution) and photochemical (water decomposition) properties, and also in high charge storage capacity devices [1-3]. Use of RuO<sub>2</sub> as an electrode material in electrochemical capacitors has many advantages. RuO2 has a high capacitance of the order of 150 to 250 microfarad/cm<sup>2</sup>, which is about ten times higher than that of carbon. Such a high value is believed to be due to pseudocapacitance from surface reaction between Ru ions and H ions. The cyclic voltammetry curve of RuO2 in an H2SO4 electrolyte is mirror-like and mainly featureless within a potential range of 1.4 V. Because of these properties, RuO<sub>2</sub> is considered attractive material for electrochemical capacitors [4]. Even though RuO<sub>2</sub> has a great advantage in terms of a wide potential range of highly reversible redox reactions with high specific capacitance, it is somewhat expensive for commercial electrodes in bulk, like electrochemical capacitors. Therefore, it is desirable to develop a thin film process for the preparation of RuO<sub>2</sub> electrode in order to reduce the cost of capacitor electrodes.

Ruthenium oxide thin films have been prepared using various techniques, including reactive sputtering [5], organometallic chemical vapor deposition [6], sol gel [1, 2, 7], electrodeposition [8–11] etc. Out of these, electrodeposition is a candidate method for the deposition of RuO<sub>2</sub> films. It offers rigid control by film thickness, uniformity, and deposition rate and is especially attractive owing to its low equipment cost and starting materials. Due to the use of an electric field, electrodeposition is particularly suited for the formation of uniform films on substrates of complicated shapes, impregnation of porous substrates and deposition on selected areas of the substrates [12]. The electrodeposition process is capable of forming thin films without the requirement of controlling atmosphere. The process is conducted at relatively low temperatures and therefore,

in general, it results into an amorphous or nanocrystalline form of material. The amorphous or nanocrystalline form of ruthenium oxide is desired as it has a larger surface area than its crystalline form, which is essential for getting the high value of capacitance in electrochemical supercapacitors.

Cathodic electrodeposition of Ruthenium oxide thin films was carried out onto titanium substrates from an aqueous acidic ruthenium chloride (RuCl<sub>3</sub>·xH<sub>2</sub>O) solution. A freshly prepared 0.04 molar solution was used. The deposition was carried out at 50 °C bath temperature. A platinum sheet was used as a counter electrode. Prior to deposition, titanium substrates  $(1 \times 1 \text{ cm}^2)$  were mechanically scrubbed by polish paper, degreased with soap and distilled water, and ultrasonically cleaned. A scanning potentiostat/galvanostat (E G & G PAR model-273A) was used in galvanostatic mode. Good quality RuO<sub>2</sub> films were deposited at current densities of  $5.0 \text{ mA/cm}^2$  on titanium substrate. Depending upon film thickness, the deposition time period was varied between 30-210 min. After deposition, RuO2 films were dried in a furnace at 373 K.

Thin films of RuO<sub>2</sub> were characterized using the following techniques. The X-ray diffraction (XRD) patterns were obtained by using X-ray diffractrometer (RINT/PMAX 2500, Rigaku, Japan). Micro structural studies were carried out with scanning electron micrographs, obtained with FE-SEM, (SM-6340F, Jeol, Japan). The electrochemical capacitance study of RuO<sub>2</sub> electrode was carried out using a conventional three-electrode system using Pt counter electrode  $(2 \times 2 \text{ cm}^2 \text{ area})$  and Ag/AgCl reference electrode. The cyclic voltammogram (CV) curves were obtained in the 0.5 MH<sub>2</sub>SO<sub>4</sub> solutions using scanning potentiostat. For charge-discharge studies of RuO2 electrode, a unit cell was assembled with positive and negative electrodes, which were kept apart by the polypropylene separator. The unit cell was immersed in the 0.5 M H<sub>2</sub>SO<sub>4</sub> solution and the galvanostatic charge-discharge test was

performed using automatic battery cycler (WBCS 3000) at a current of 3 mA in the voltage range of 0 to +0.8 V.

and,

$$2H_2O + 2e^- \leftrightarrow H_2 + 2OH^-$$
(2)

It was pointed out that electrodeposition is similar to the wet chemical method of oxide powder processing, making use of an electrogenerated base instead of alkali [8, 9, 13]. In the deposition from an aqueous bath the following reactions are considered to generate base at an electrode surface:

$$O_2 + 2H_2O + 4e^- \leftrightarrow 4OH^- \tag{1}$$

These reactions consume  $H_2O$ , generate  $OH^-$  and increase pH at the cathode. In electrodeposition, metal ions or complexes are hydrolyzed by electrogenerated base to form oxide, hydroxide or peroxide deposits on cathodic substrates. Hydroxide and peroxide deposits can be converted into corresponding oxides by thermal treatment. Hydrolysis reactions result in



*Figure 1* The variation of  $RuO_2$  film weight (g/cm<sup>2</sup>) on titanium substrate with deposition time period. The  $RuO_2$  films were deposited at deposition current density of 5.0 mA/cm<sup>2</sup>.



*Figure 2* The scanning electron micrographs of RuO<sub>2</sub> films on titanium substrates at two different magnifications: (a)  $1000 \times$  and (b)  $5000 \times$ . The films were deposited for 30 min at 5.0 mA /cm<sup>2</sup> current density.

the accumulation of colloidal particles near the electrode and deposition is caused by flocculation introduced by the electrolyte. Recent studies have demonstrated the formation of RuO<sub>2</sub> powders by hydrolysis of  $RuCl_3 \cdot xH_2O$  in the presence of an alkali [14]. These results suggest the possibility of forming RuO<sub>2</sub> films by electrodeposition. The mechanism of RuO<sub>2</sub> deposition is not fully understood and it is thought to be performed via the hydroxide route. Hydrated ruthenium chloride is a heterogeneous ionic material with an average ruthenium oxidation state between 3 and 4 but closer to 4. For this reason, the mechanism of formation of  $RuO_2$  from  $RuCl_3 \cdot xH_2O$  precursor is a complex one. The ruthenium species are most likely to precipitate as hydrated ruthenic oxide ( $RuO_2 \cdot xH_2O$ ) or ruthenic hydroxide Ru(OH)<sub>4</sub>. This process consumes electrochemically generated OH<sup>-</sup> ions [8, 9]. The electrodeposition potentials depend upon bath temperature, nature of substrate, metal ion concentration, complexing agent and its concentration etc.

The pH of RuCl<sub>3</sub> solution was varied in the range of 1.0 to 2.5 with the addition of hydrochloric acid solution. The suitable pH range was found to be 2.0 to 2.5. The deposition bath temperature was varied from 298 to 353 K. The suitable solution bath temperature was found to be 323 K, although RuO<sub>2</sub> films could be deposited in the above temperature range. The RuO<sub>2</sub> film thickness was increased by deposition for longer time periods. However, accurate RuO<sub>2</sub> film thickness measurement was not possible due to the high porosity of the films, therefore the deposited weight  $(g/cm^2)$ on the titanium substrate is considered instead of RuO<sub>2</sub> film thickness. Fig. 1 shows such a typical variation of RuO<sub>2</sub> film weight (g/cm<sup>2</sup>) with the deposition time period. The deposited weight of RuO<sub>2</sub> film material was increased with the deposition time and maximum weight of 0.0059 g/cm<sup>2</sup> for the deposition period of 180 min was obtained. For further deposition period, the deposited weight showed a decline, probably due to the porous structure formation of RuO<sub>2</sub> film. The





*Figure 3* The X-ray diffraction patterns of RuO<sub>2</sub> films deposited on titanium substrates for different time periods at current density of  $5.0 \text{ mA/cm}^2$  (a)  $30 \text{ min}-0.0014 \text{ g/cm}^2$ , (b)  $60 \text{ min}-0.0023 \text{ g/cm}^2$ , (c)  $120 \text{ min}-0.0040 \text{ g/cm}^2$ , and (d)  $180 \text{ min}-0.0059 \text{ g/cm}^2$ . The marks 'x' and 'O' correspond to RuO<sub>2</sub> and Ti materials, respectively.

weight of  $\text{RuO}_2$  film was typically between 0.0014 and 0.0059 g/cm<sup>2</sup>, depending upon solution pH, bath temperature, deposition current density and time. The  $\text{RuO}_2$  films were blackish in color.

The RuO<sub>2</sub> film crystallinity was analyzed using Xray diffraction. The RuO<sub>2</sub> films with different weights were deposited by changing deposition time periods. In Fig. 2, X-ray diffraction spectra are shown corresponding to RuO<sub>2</sub> films of different weights on titanium substrates. The peak intensity of titanium substrate was reduced with the increasing thickness (weight/cm<sup>2</sup>) of RuO<sub>2</sub> film. Practically, no difference was observed between XRD patterns corresponding to the different asdeposited RuO<sub>2</sub> films on the titanium substrates, which indicates the identical growth directions for RuO<sub>2</sub> films. The intensities of peaks corresponding to RuO<sub>2</sub> were increased with the increasing film weight. The peak corresponding to d-value of 2.05 Å could not be resolved well, as it can be attributed to both, deposition of metallic ruthenium or ruthenium oxide [15]. However, deposition of metallic ruthenium from aqueous bath is unlikely [8, 9] and therefore, the corresponding peak may be attributed to the  $RuO_2$  [15]. The broadening of  $RuO_2$  peaks suggests that the deposited  $RuO_2$ consists of grains of nanometer size. The small grained or amorphous RuO<sub>2</sub> films have been also reported from cyclic voltametry method [16].

Scanning electron micrographs of  $RuO_2$  film on titanium substrate at two different magnifications  $(1,000 \times \text{ and } 5,000 \times)$  are shown in Fig. 3a and b. At  $1000 \times$  magnification,  $RuO_2$  film surface showed cracks and peeling off from the substrate. At high magnification  $(5000 \times)$ , a  $RuO_2$  film with porous structure is clearly visible, similar to those of other chemical methods such as cyclic voltametry [1, 16], sol–gel [2], spray pyrolysis [17] etc.

In case of  $\text{RuO}_2$  based electrochemical supercapacitor, the capacitance comes mainly due to the pseudocapacitance of  $\text{RuO}_2$  by surface redox reactions between electrolytes and  $\text{RuO}_2$  electrode [1, 4]. The specific capacitance (F/g) is proportional to the specific surface area. Therefore, it is important to get more surface area of  $\text{RuO}_2$  material. It is demonstrated that amorphous or nanocrystalline form of hydrous ruthenium oxide as an electrode has a much higher specific capacitance than that of the crystalline form of ruthenium oxide [10].

The electrodeposited nanocrystalline RuO<sub>2</sub> films were used in the formation of electrochemical supercapacitors and their performance was tested by studying CV curves and charge-discharge cycles. The CV curves showed that voltametric current decreases with increasing sweep cycles and stable currents are obtained after about 7-8 cycles. Fig. 4 shows the CV curves of RuO<sub>2</sub> thin films with different weights at scanning rate of 20 mV/sec. It is seen that voltametric currents gradually increased with film weight  $(g/cm^2)$  and showed capacitive behavior. Only some broad peaks were obtained and the CV curves are mainly featureless and indicated that this material is ideal for use as a capacitor electrode. The featureless curve is also indicative that the charge exchange between RuO<sub>2</sub> and electrolyte is independent of voltage [1].

From these data, capacitance was calculated for different weights of  $RuO_2$  material deposited on titanium substrates, using the following relation:

$$C = I(A)/(\mathrm{d}V/\mathrm{d}t),\tag{3}$$

Where *I* is the average current in ampere and dV/dt is the voltage scanning rate. The specific capacitance of RuO<sub>2</sub> was obtained by dividing their respective weight. The variation of specific capacitance with deposited



*Figure 4* Cyclic voltammogram (CV) curves of RuO<sub>2</sub> films in 0.5 M H<sub>2</sub>SO<sub>4</sub> electrolyte, deposited for different deposition time periods: (a) 30 min–0.0014 g/cm<sup>2</sup>, (b) 60 min–0.0023 g/cm<sup>2</sup>, (c) 120 min–0.0040 g/cm<sup>2</sup>, and (d) 180 min–0.0059 g/cm<sup>2</sup>. The scanning rate is 10 mV/sec.

weight of  $\text{RuO}_2$  films showed the magnitudes as high as 788 F/g for the  $\text{RuO}_2$  film deposited for 30 min (film weight, 0.0014 g/cm<sup>2</sup>). This value is comparable to the values obtained with other methods of  $\text{RuO}_2$  film deposition [1, 2, 11]. The charging-discharging behavior of electrochemical supercapacitor formed with  $\text{RuO}_2$ electrode was studied. The behavior showed that  $\text{RuO}_2$ electrodes are stable in the H<sub>2</sub>SO<sub>4</sub> electrolyte.

In conclusion, using a simple cathodic electrodeposition method,  $RuO_2$  films are deposited on titanium substrates. The  $RuO_2$  films are nanocrystalline and porous. The supercapacitor studies based on nanocrystalline  $RuO_2$  films showed that specific capacitance as high as 788 F/g is obtained, which is comparable with the values of other methods of  $RuO_2$  film preparation.

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